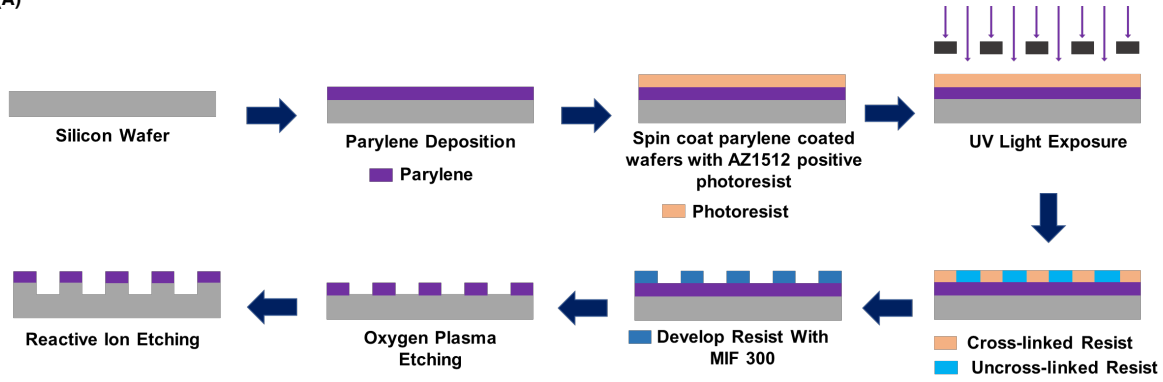
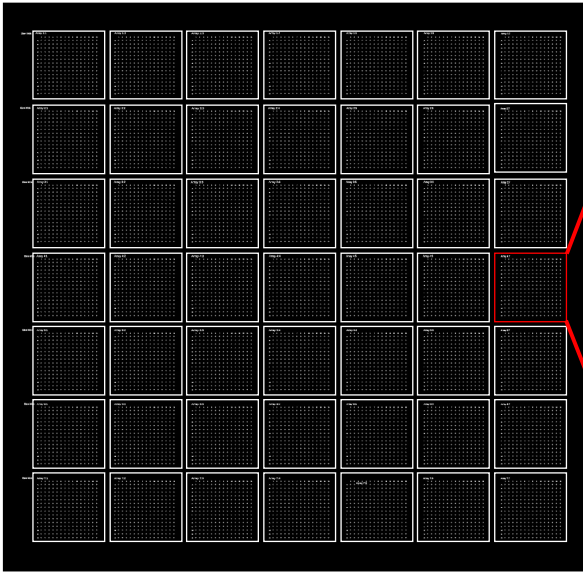
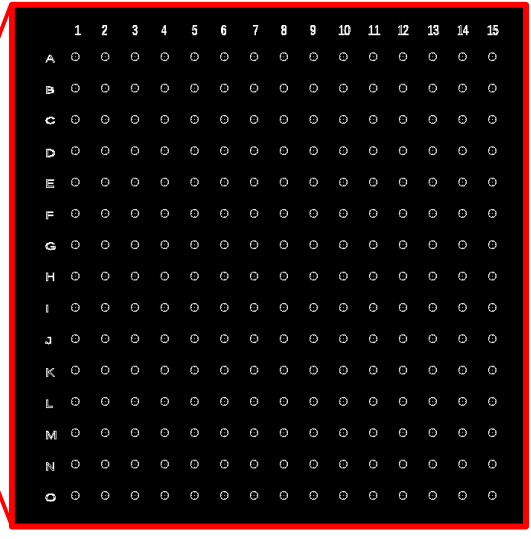
(A)


Silicon Wafer
Parylene Deposition
Parylene
Spin coat parylene coated wafers with AZ1512 positive photoresist
Photoresist
UV Light Exposure
Cross-linked Resist
Uncross-linked Resist
Develop Resist With MIF 300
Oxygen Plasma Etching
Reactive Ion Etching

(B)



(C)


1 2 3 4 5 6 7 8 9 10 11 12 13 14 15
A B C D E F G H I J K L M N O